

Studying Target Erosion in Planar Sputtering Magnetrons Using a Discrete Model for Energetic Electrons

C. Feist* | CENUMERICS | Austria

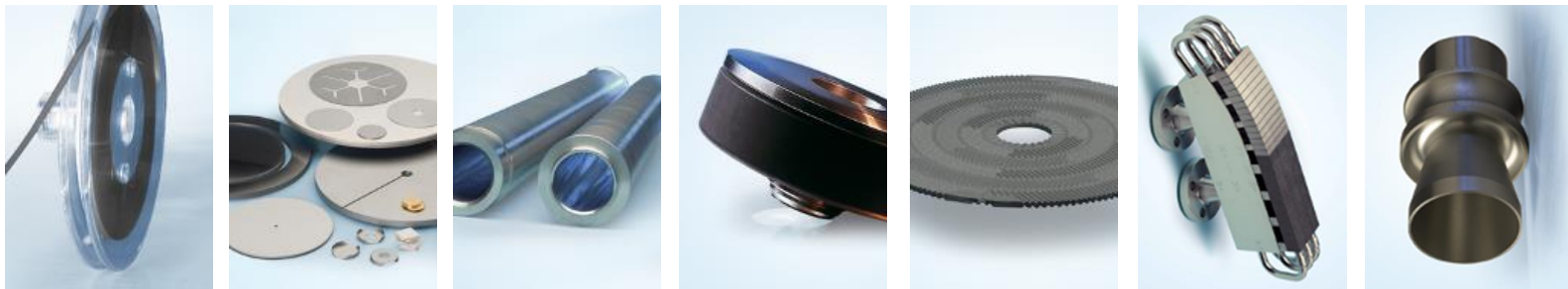
A. Plankensteiner, J. Winkler | PLANSEE SE | Austria

PLANSEE SE

- founded in 1921 for production of molybdenum (Mo) and tungsten (W) wires
- annual turnover: € 1,500 M+ • employees: 6,000+ worldwide (2012)
- world market leader in P/M production of refractory metals



used in wide range of high-tech applications and industries:
lighting, medical, power generation, aerospace ...



unique combination of material properties:

- high melting point
- excellent high temperature strength

Sputtering process

- PVD (physical vapor deposition) process
- for thin film deposition
- on various substrates
- source material (e.g. Mo and W)
- sputtered from “targets” by ion bombardment
- established by gas discharge

PLANSEE’s twofold role in sputtering

- supplier of targets made from Mo and W
- user of sputtering process for in-house coating



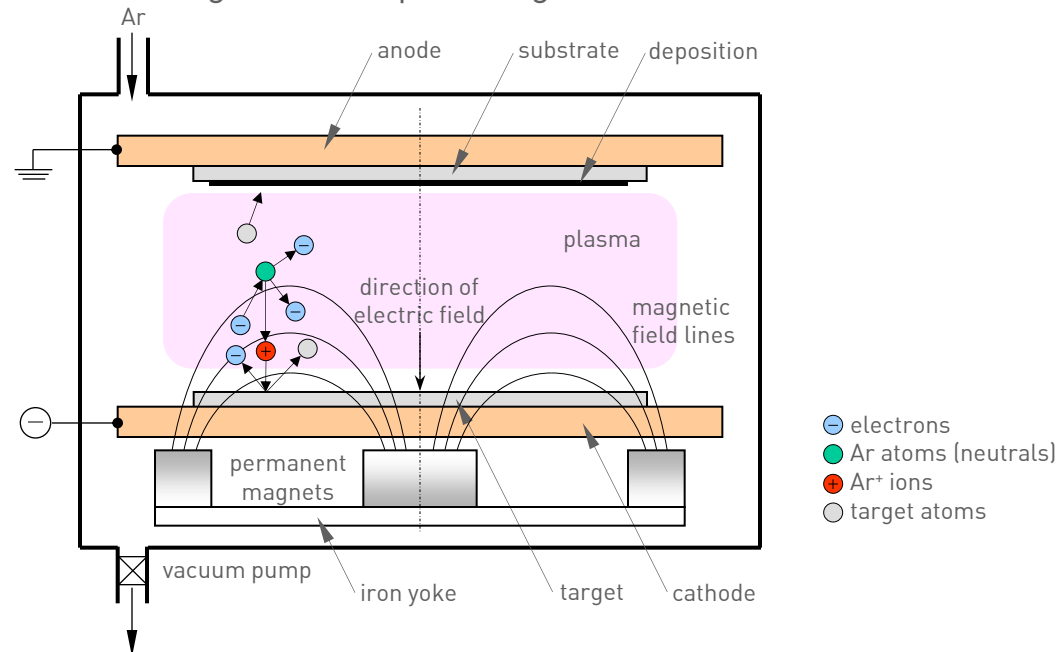
In-line sputtering system for display panel production
(Ulvac)



Target-configuration for metal strip coating
(Von Ardenne)

The magnetron sputtering process

- operated in vacuum chamber (typical pressure: $10^{-1} - 10^0$ Pa)
- target bonded onto cathode
- geometric layouts depending on field of application
- DC discharge:
 - stationary electric field between grounded anode and
 - cathode subjected to negative bias (typically: -200 to -400 V)
 - formation of plasma with cathode fall (plasma sheath)
 - using background gas, e.g. argon (Ar)
- magnetically enhanced: static magnetic field providing “confinement” to electrons



Magnetic confinement of energetic electrons

advantages:

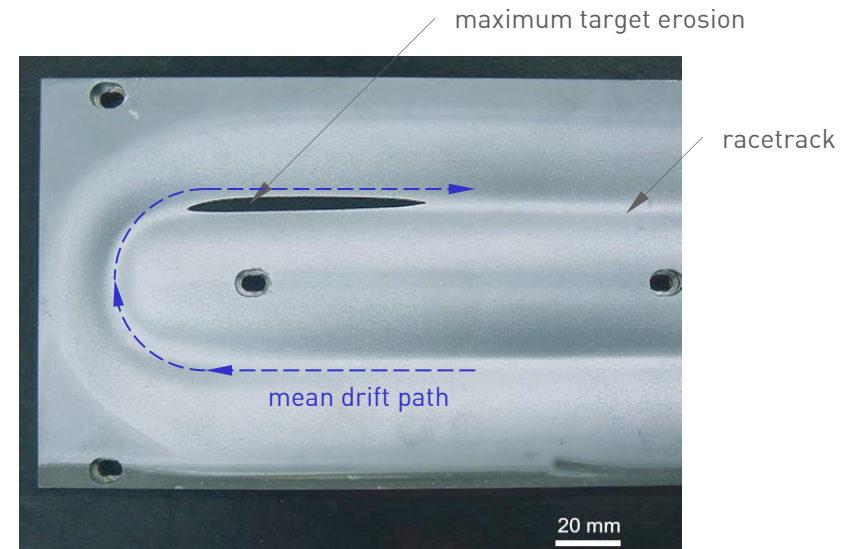
- increased ionization and sputtering rate
 - allows reducing operating pressure
 - reduced spurious depositions
 - higher deposition quality

drawbacks:

- non-uniform ion flux onto target
 - non-uniform target erosion
 - reduced target utilization (typically: ~ 20 – 40 %)
- rectangular targets: *cross corner effect* (CCE)

Objective

- improve uniformity of target erosion
- increase target utilization
- by means of numerical simulation
 - implementation and verification of model
 - for prediction of relative ion flux and target erosion



Q.H. Fan et al.; J.Phys. D: Appl. Phys. 36(2003) 244-251.

Trajectories of charged particles without collisions

Lorentz force

acting on particle of charge q
from electromagnetic fields \mathbf{E} and \mathbf{B}

$$\mathbf{F} = q\mathbf{E} + q\dot{\mathbf{x}} \times \mathbf{B}$$

+ *Newton's equation of motion*

for particle of constant mass m

= system of second order ODEs

in terms of components of particle position vector \mathbf{x}
to be solved for each particle under consideration

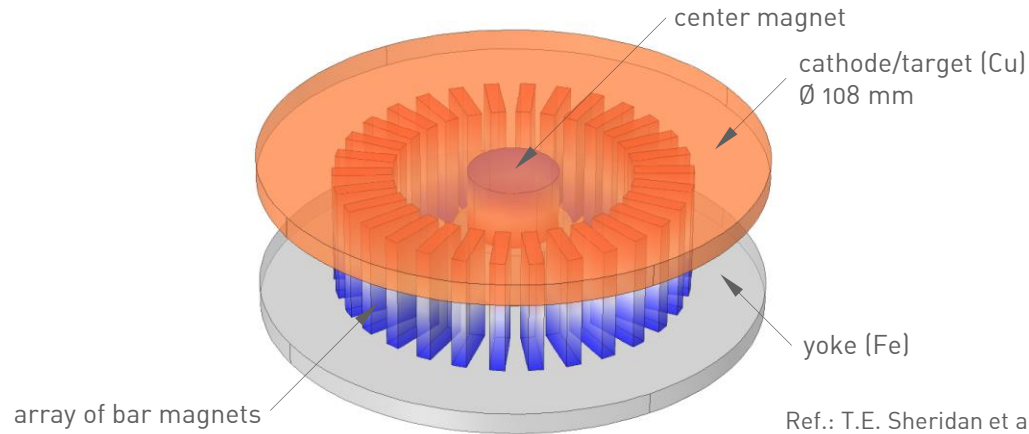
$$\ddot{\mathbf{x}} = \frac{q}{m}(\mathbf{E}(\mathbf{x}) + \dot{\mathbf{x}} \times \mathbf{B}(\mathbf{x}))$$

Assumptions and involved simplifications

- magnetic field induced by current through plasma neglected (*Maxwell-Ampere's law*)
→ static magnetic field from permanent magnets computed *a priori*
- electric field computed *a priori* from reasonable estimate for number densities (*Poisson's law*)
→ allows sequential coupling
→ no self-consistent solution

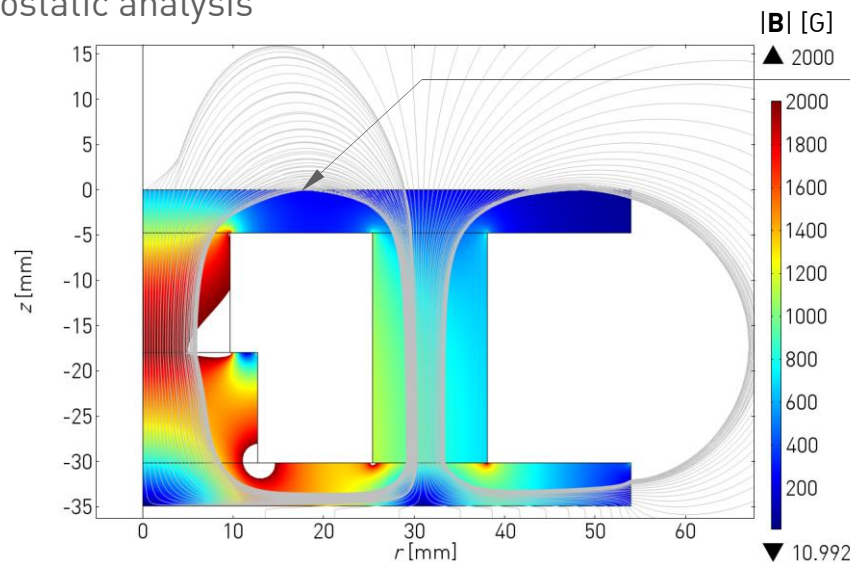
Benchmark example - axisymmetric DC magnetron

geometry



Ref.: T.E. Sheridan et al.; J. Vac. Sci. Technol. A; Vol. 8(1); 1990.

results from magnetostatic analysis



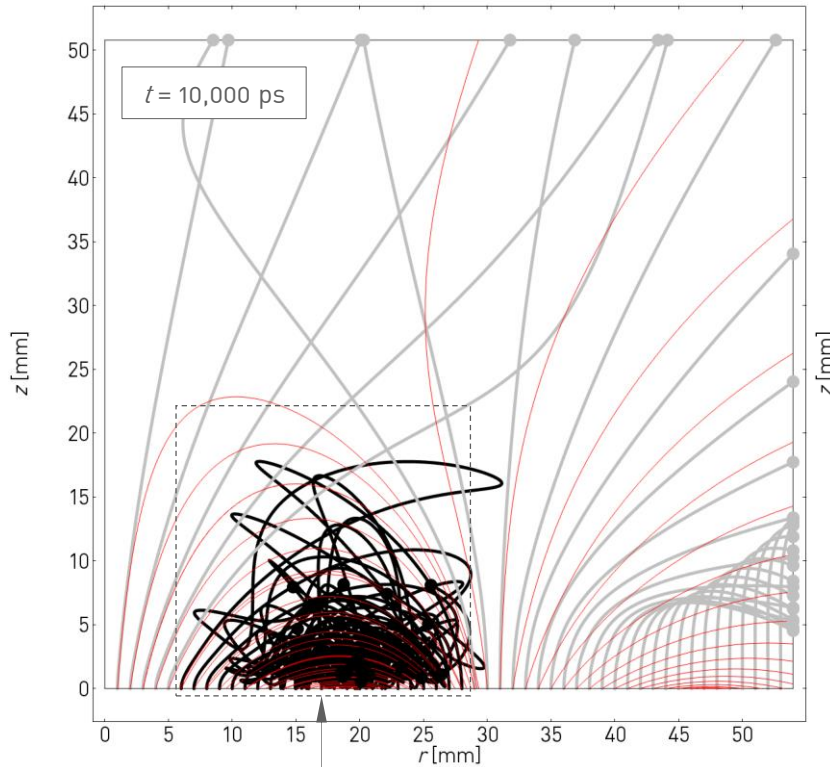
$r \approx 19$ mm: $B_z = 0$
 from experience known as
 location of maximum erosion

Benchmark example - axisymmetric DC magnetron

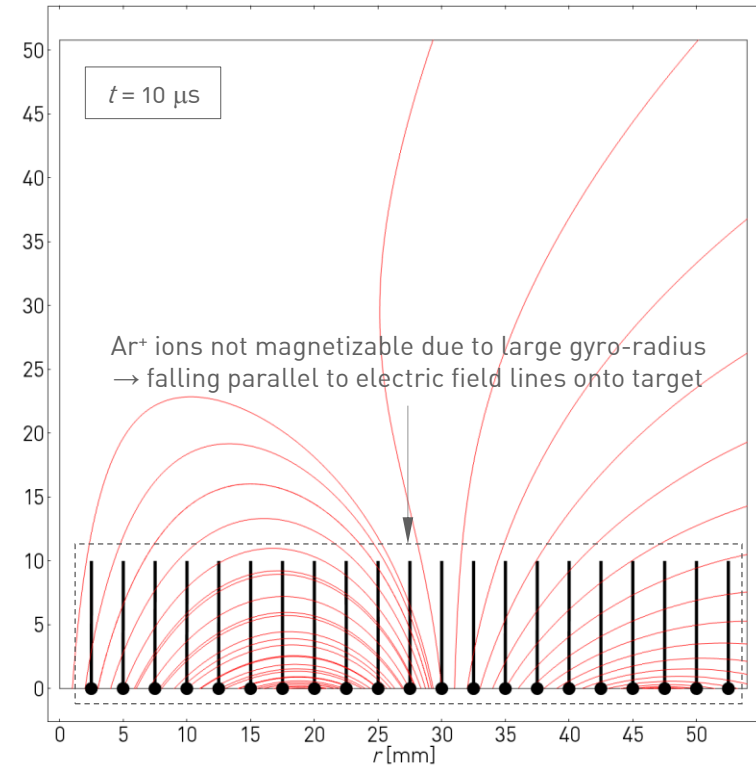
preliminary assessment of trajectories of charged particle species

electrons released from target
(secondary electron emission)

ions created in plasma (ionization)



electrons confined by magnetic field



Ar⁺ ions not magnetizable due to large gyro-radius
→ falling parallel to electric field lines onto target

- particle trajectories
- unconfined electrons
- magnetic flux density streamlines

Modeling strategy

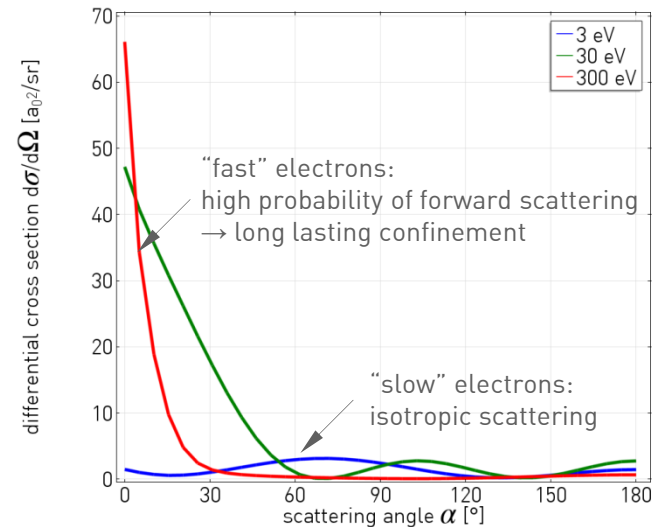
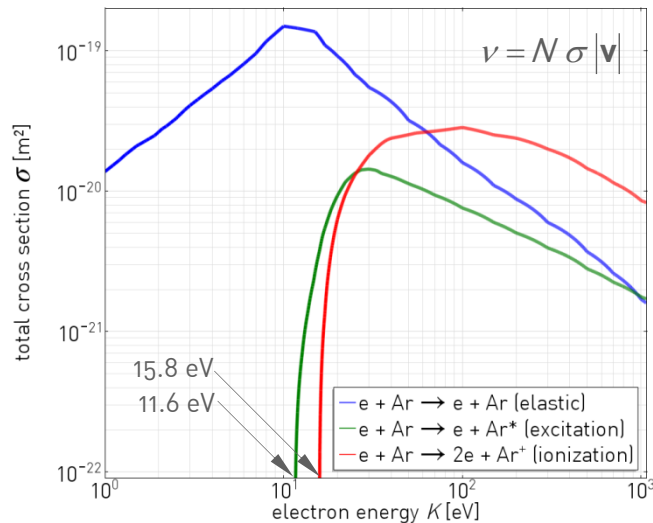
workflow

- initialize electron emission flux distribution $j_e(r)$ on target
 - loop over:
 - release set of electrons from target based on $j_e(r)$
 - integrate electron trajectories
 - account for collisions and scattering at random time instants by velocity re-initialization
 - project locations of ionization collisions onto target = ion bombardment flux $j_i(r)$
 - obtain improved electron emission flux distribution $j_e(r) = \gamma j_i(r)$
- until $j_e(r)$ converged

electron collision modeling for argon (Ar) as background gas

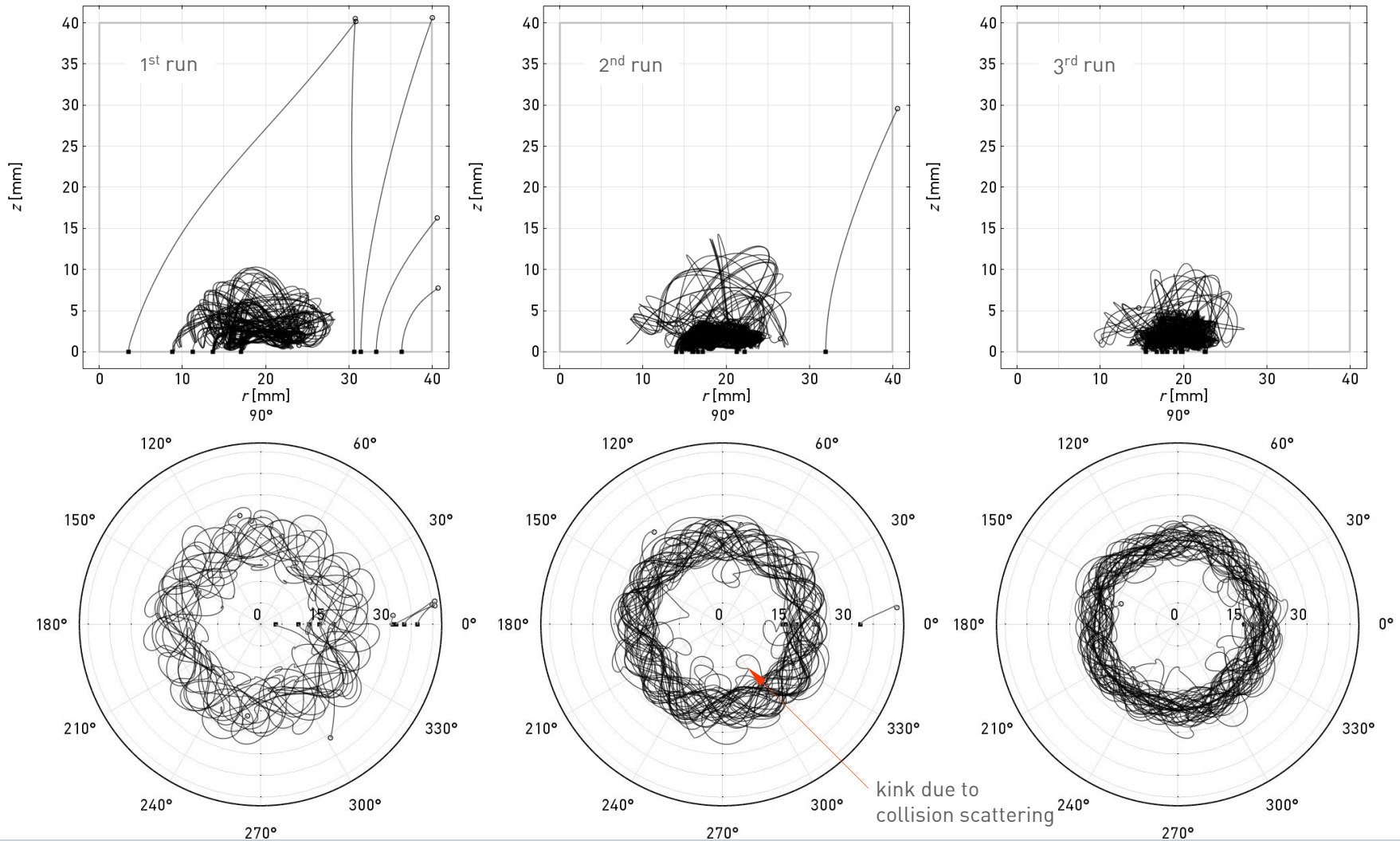
collision frequency ν from total cross section σ

scattering angle α from differential cross section $d\sigma/d\Omega$



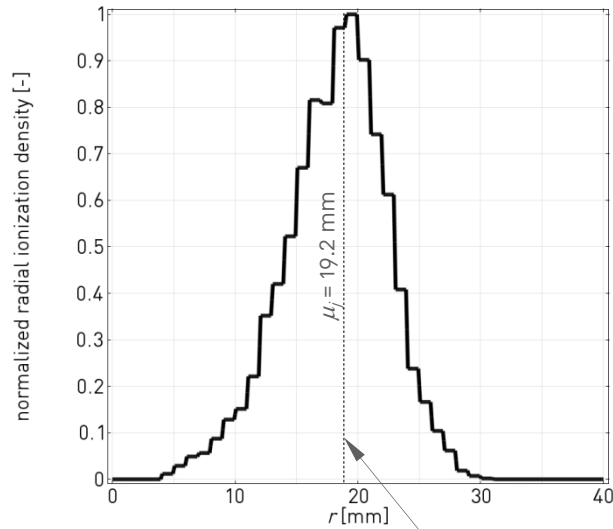
Application to benchmark example

electron trajectories in rz - and $r\phi$ -plane for 3 consecutive runs (after initial $0.1 \mu\text{s}$ for 10 electrons)



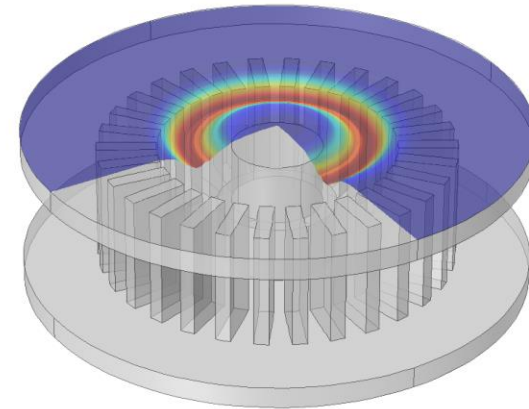
Application to benchmark example

integral results after 7 runs over $1.0 \mu\text{s}$
 normalized ion flux density on target $j_i(r)$



$$\dot{w} \propto j_i(r)$$

estimate for relative target erosion w
(normalized by target thickness)



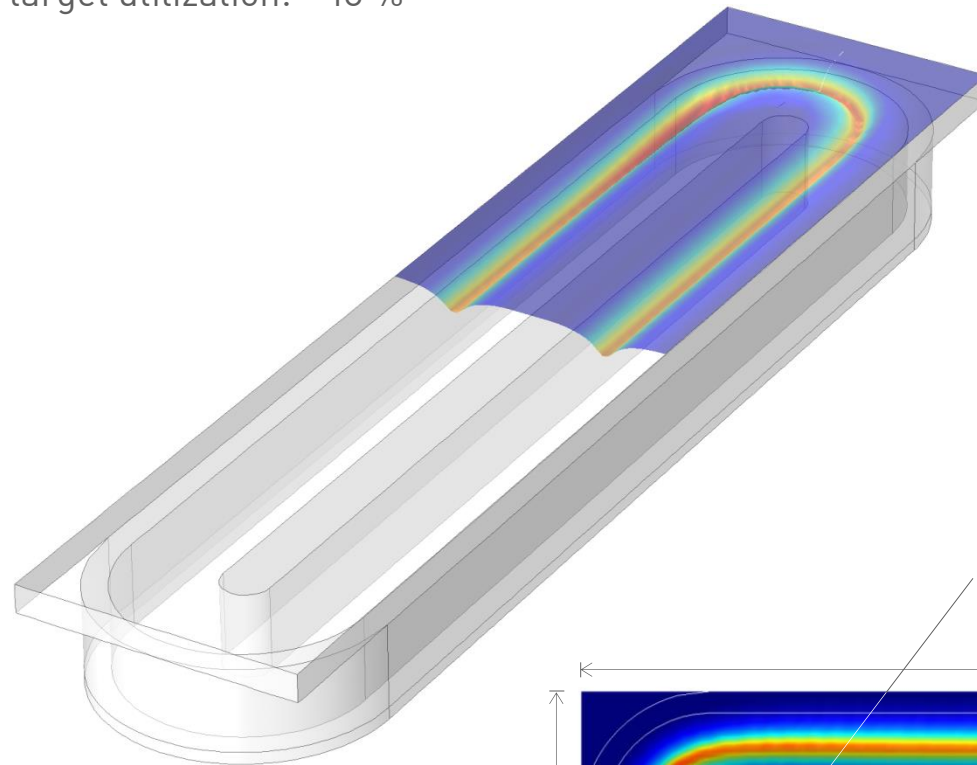
$r \approx 19 \text{ mm}: B_z = 0$

Note:

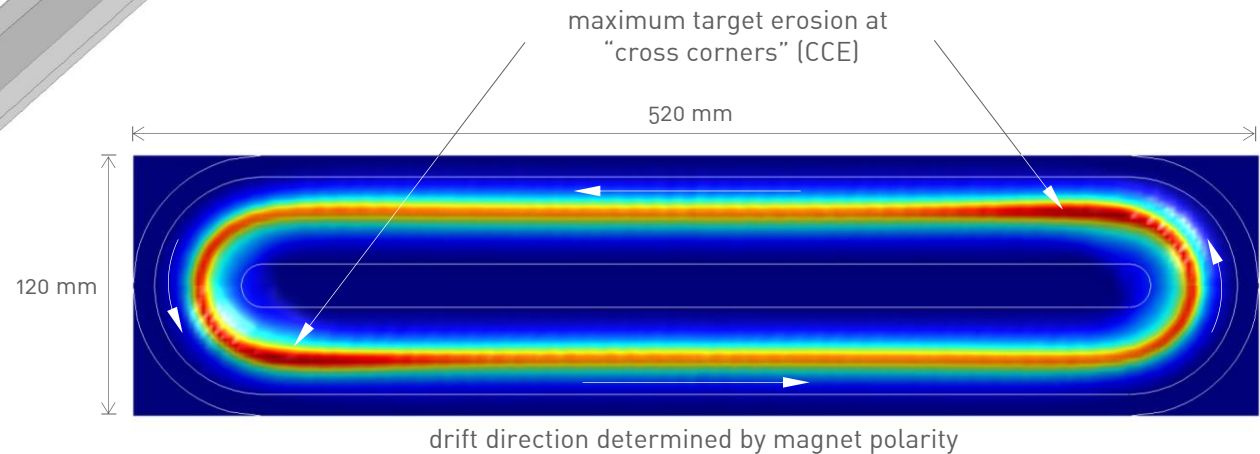
location of maximum ionization flux and target erosion
 = location of vanishing normal magnetic field

Application to rectangular planar magnetron





estimate of target erosion w (normalized to target thickness of 12 mm) using 5,000 electrons
target utilization: ~ 18 %



Ref.: Q.H. Fan et al.; J.Phys. D: Appl. Phys. 36(2003) 244-251.



Summary

- discrete model for energetic electrons acc. to *Sheridan* and coworkers
- for prediction of relative Ar⁺ ion flux and erosion rate
- of planar target in DC sputtering magnetron
- to study design modifications for increased target utilization (ongoing work)
- implemented using COMSOL Multiphysics 4.3a
 - benefit: unified framework, no data exchange
- employed interfaces:
 - B-field:  Magnetic Fields, No Currents (mfnc)
 - particle trajectories:  Point ODEs and DAEs (pode)
 - particle collisions:  Events (ev)
 - collision statistics:  Boundary ODEs and DAEs (bode)

Why not DC Discharge (dc)

- computational costs resulting from required spatial and time discretization
- severe anisotropy of mobility/diffusivity tensors
- simple plasma-physics (Ar)

Why not Charged Particle Tracing (cpt)

- collision feature not available in 4.3a (new in 4.3b)
- collision statistics not feasible (even in 4.3b)
- events interface not usable together with particle tracing

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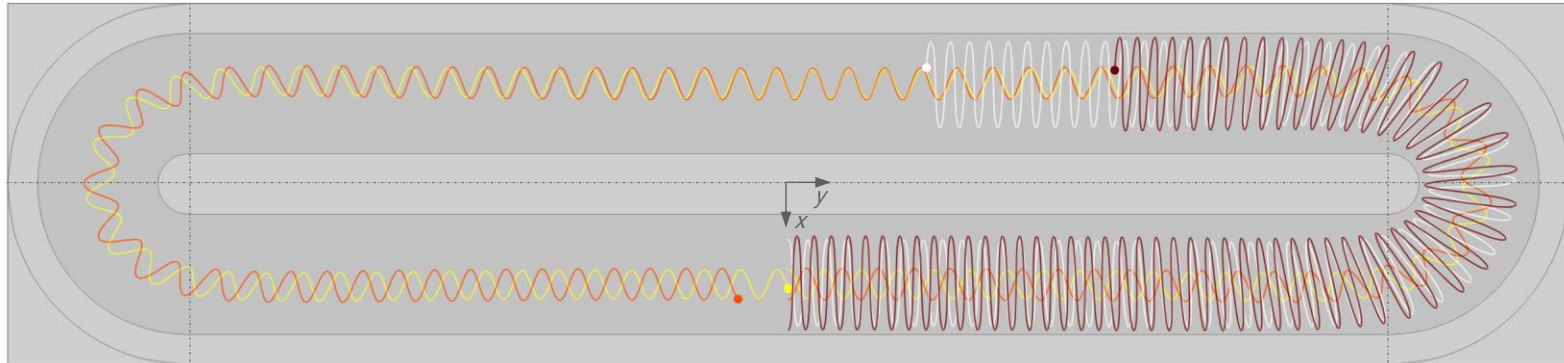
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... thanking you for your interest

Application to rectangular planar magnetron

exemplary trajectories of electrons starting at $y = 0$ and $x = 18.5 : 10 : 48.5$ mm over $0.428 \mu\text{s}$ (1 rev)



$x_0 = x(t=0)$ [mm]

▼ 18.5



▲ 48.5

